

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

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| Applicants: | Nishio, et al. | Docket No.: | 49288.2800 |
| Serial No.: | 10/595,201 | Examiner: | Laura M. Lee |
| Filed: | January 2, 2007 | Group Art Unit: | 3724 |
| Title: | SUBSTRATE DICING SYSTEM, SUBSTRATE MANUFACTURING APPARATUS, AND SUBSTRATE DICING METHOD | Confirmation No.: | 4462 |

AMENDMENT AND REPLY

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Commissioner:

In reply to the Office Action dated June 18, 2009, of which this Reply is within the shortened one month period for reply, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.